

# **METHOD FOR MEASURING DIMENSIONS OF MINUTE STRUCTURES AND APPARATUS FOR PERFORMING THE SAME**

## **ABSTRACT OF THE DISCLOSURE**

5           A method for measuring dimensions of minute structures on a substrate  
include irradiating primary electrons onto the minute structures, and detecting  
secondary electrons generated from the minute structures. Image data of the  
minute structures is formed, and at least two measuring regions are determined  
over the minute structures using the image data. The dimensions of the minute  
10       structures corresponding to the measuring regions are calculated. The primary  
electrons are provided from an electron emission member to the minute  
structures, and the secondary electrons are converted into current signals and  
then imaged in a displaying member. An operation member calculates the  
dimensions of the minute structures corresponding to the measuring regions  
15       using the image data of the minute structures stored in a storage member and  
measurement data that is measured at the measuring regions.